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REMARKS

STATUS OF THE CLAIMS

1. (Original) A chemical vapor deposition process for the preparation of a single-wall carbon

nanotube, comprising:

contacting a carbon-containing gas composition with a porous membrane having a first side

and a second side, wherein the first side is opposite to the second side, and wherein a thin

catalyst layer is present on at least the first side of the membrane.

at a temperature sufficient to decompose said carbon-containing gas composition in the

presence of said catalyst causing growth of a single-wall carbon nanotube,

wherein a pressure differential exists across the porous membrane, the pressure on the

second side being less than that on the first side.

2. (Original) The process according to claim 1, wherein said growth of a single-wall carbon

nanotube predominantly occurs on the second side of said porous membrane.

3. (Original) The process according to claim 1, wherein said growth of a single-wall carbon

nanotube predominantly occurs between the catalyst and the first side of the porous

membrane.

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4. (Original) The process according to claim 1, wherein said thin catalyst layer is present only

on the first side of said porous membrane.

(Original) The process according to claim 1, wherein said carbon-containing gas

composition comprises methane gas.

6. (Original) The process according to claim 5, wherein said carbon-containing gas

composition comprises methane, hydrogen, and an inert gas.

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(Original) The process according to claim 6, wherein said inert gas is argon gas.

8. (Original) The process according to claim 1, wherein said porous membrane has a particle

size less than about 2 micron.

9. (Original) The process according to claim 8, wherein said membrane has a particle size less

than about 500 nm.

10. (Original) The process according to claim 1, wherein said porous membrane is selected

from the group consisting of; alumina and stainless steel.

11. (Original) The process according to claim 1, wherein said catalyst is a catalyst composition

comprising iron and molybdenum.

(Original) The process according to claim 11, wherein said catalyst composition further

comprises alumina.

13. (Original) The process according to claim 1, wherein said temperature sufficient to

decompose the carbon-containing gas ranges from about 670°C to about 800°C.

14. (Original) The process according to claim 1, wherein said pressure differential ranges from

about 50 to about 500 Torr.

15. (Original) The process according to claim 14, wherein said pressure differential ranges from

about 200 to about 300 Torr.

(Original) A chemical vapor deposition process for producing a single-wall carbon

nanotube, comprising:

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A chemical vapor deposition process for producing a single-wall carbon nanotube,

comprising:

17. (Original) The process according to claim 16, wherein the ratio of Al₂0₃: Fe in said catalyst

composition ranges from about 50:1 to about 2:1, the ratio of $\mathrm{AI}_20_3{:}\mathrm{Mo}$ in said catalyst

composition ranges from about 100:1 to about 5:1, and the ratio of Fe:Mo in said catalyst

composition ranges from about 15:1 to about 1:2.

18. (Original) The process according to claim 17, wherein said catalyst has a ratio of

A1203:Fe:Mo of about 9:1: 1/3.

(Original) The process according to claim 16, wherein said inert gas is argon gas.

20. (Original) The process according to claim 16, wherein the ratio of methane; hydrogen in

said carbon-containing gas composition ranges from about 5:1 to about 1:5 by volume, the

ratio of methane:inert gas in said carbon-containing gas composition ranges from about 1:2

to about 1:50 by volume, and the ratio of hydrogen:inert gas in said carbon-containing gas

composition ranges from about 1:2 to about 1:50 by volume.

21. (Original) The process according to claim 20, wherein said carbon-containing gas

composition has a ratio of methane: hydrogen: inert gas of about 1:1:10 by volume.

22. (Withdrawn) An apparatus for conducting a chemical vapor deposition process, comprising:

a first tube and a second tube, said first tube disposed at least within a portion of the second

tube, said first tube including a first opening and a second opening, said first opening facing

the interior of the second tube, and said second opening being coupled to

a vacium:

a porous membrane contiguous to the first opening; and

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a thin catalyst layer contiguous to the at least a portion of said porous membrane that faces

the interior of the second tube;

 (Withdrawn) The apparatus of claim 22, wherein said porous membrane cinctures said first opening.

 (Withdrawn) The apparatus of claim 22, wherein said porous membrane has a particle size less than about 2 micron.

25. (Withdrawn) The apparatus of claim 24, wherein said membrane has a particle size

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RESPONSE TO RESTRICTION REQUIREMENT

In the Office Action, the Examiner restricted the claims to two groups. The Examiner

therein required election of one of the following groups of claims:

Group I, claims 1-21, drawn to a process for synthesizing carbon nanotubes (classified in

class 427, subclass 249.1);

Group II, claims 22-25, drawn to an apparatus for production of carbon nanotubes

(classified in class 118, subclass 500+).

Applicants provisionally elect Group I comprising claims 1-21, drawn to a process for

synthesizing carbon nanotubes, without traverse.

CONCLUSION

Consideration of the claims is respectfully requested, and a notice of allowance is earnestly

solicited. If the Examiner has any questions concerning this Amendment, the Examiner is invited to

telephone Applicants' representative at (650) 335-7818.

Respectfully submitted, Leonid Grigorian et al.

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